



501.40830X00

Applicants: T. HIROI et al

Serial No.: 09/986,299

Filed: November 8, 2001

For: Pattern Inspection Method and Apparatus

Art Unit: 2625

Examiner: J. Strege

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DEC 0 9 2004

Technology Center 2600

**AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

December 3, 2004

Sir:

This is in response to the Office Action mailed September 3, 2004, in connection with the above-identified application. The amendments are listed below and set forth on the following pages.

Amendments to the Specification;

Amendments to the Claims; and

Remarks are included following the amendments.